



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: STEGER

Examiner: UNKNOWN PRUCHNICK

Application No. 10/720,839

Group No. ~~2858~~ 2859

Filed: 11/24/2003

Confirmation No. 3615

Title: METHODS AND APPARATUS FOR  
IN SITU SUBSTRATE TEMPERATURE  
MONITORINGINFORMATION DISCLOSURE STATEMENT

## US PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	Reference to Related Cases
SOX	1	6514376 B1	2003-02-04	Collins et al.	<del>CL/5WS</del>
	2	6605955 B1	2003-08-12	Costello et al.	-/-
	3	6635117 B1	2003-10-21	Kinnard et al.	-/-
	<del>4</del>	<del>4919542</del>	<del>1990-04-24</del>	<del>Nulman et al.</del>	<del>ALREADY CITED BY EXAMINER</del>
	5	5200023	1993-04-06	Gifford et al.	-/-
	6	5229303	1993-07-20	Donnelly, Jr. et al.	-/-
	7	5388909	1995-02-14	Johnson et al.	-/-
	8	5467732	1995-11-21	Donnelly, Jr. Et al.	-/-
	9	5490728	1996-02-13	Schietinger et al.	-/-
	10	5568978	1996-10-29	Johnson et al.	-/-
	11	5660472	1997-08-26	Peuse et al.	-/-
	12	5683180	1997-11-04	De Lyon et al.	-/-
	13	5746513	1998-05-05	Renken	-/-
	14	5755511	1998-05-26	Peuse et al.	-/-
	15	5769540	1998-06-23	Schietinger et al.	-/-
	16	5775808	1998-07-07	Pan	-/-
	17	5848842	1998-12-15	Peuse et al.	-/-
	18	5967661	1999-10-19	Renken et al.	-/-
	19	5996415	1999-12-07	Stanke et al.	-/-
	<del>20</del>	<del>6062729</del>	<del>2000-05-16</del>	<del>Ni et al.</del>	<del>ALREADY CITED</del>
	21	6082892	2000-07-04	Adel et al.	-/-
	22	6112595	2000-09-05	Stanke et al.	-/-
	23	6174080	2001-01-16	Jennings	-/-
	24	6179466	2001-01-30	Peuse et al.	-/-
SOX	25	6182510	2001-02-06	Stanke et al.	-/-
	26	6481886	2002-11-19	Narendmath et al.	-/-

## OTHER DOCUMENTS

Examiner Initials	Cite No.	Description	T
SOX	27	Hirscher, Hans, "Electrostatic Chuck to Boost Your Yield", (NO DATE) <a href="http://semiconductors.unaxis.com/en/chiponline_72dpi/issue5/c5p39_72.pdf">http://semiconductors.unaxis.com/en/chiponline_72dpi/issue5/c5p39_72.pdf</a>	
SOX	28	"Diffuse-Reflectance Infrared Fourier Transform (DRIFT) Spectroscopy", (NO DATE) <a href="http://147.46.41.146/C~Jii/DRIFT.htm">http://147.46.41.146/C~Jii/DRIFT.htm</a>	
SOX	29	"DRS-1000™ vs. Other Techniques", <a href="http://www.thermionics.com/drs/drsvspry.htm">http://www.thermionics.com/drs/drsvspry.htm</a> (NO DATE)	

EXAMINER: Stanley J. Pruchnick, Jr. Considered 5/16/05

10/720,839

508	30	"Chapter 6: Thermal Mass", <a href="http://www.seav.vic.gov.au/ftp/buildings/5starhousing/ESHousingManualCh06.pdf">http://www.seav.vic.gov.au/ftp/buildings/5starhousing/ESHousingManualCh06.pdf</a>	(NO DATE)
	31	Ellingboe, Bert, " Plasma Processing in the Microelectronics Industry", <a href="http://www.physics.dcu.ie/~jpm/seminars/seminars00_01/intro_to_plasma_processing.PDF">http://www.physics.dcu.ie/~jpm/seminars/seminars00_01/intro_to_plasma_processing.PDF</a>	(NO DATE)
	32	"In-Situ 4000 White Paper – Solving the problems of pyrometry and thickness measurement during MBE and MOCVD", <a href="http://www.svta.com/products/monitoring/IS4K_White%20Paper.pdf">http://www.svta.com/products/monitoring/IS4K_White%20Paper.pdf</a>	(NO DATE)
	33	Thevenard, Laura, "Wafer Temperature Measurement by Infrared Spectroscopy", Ecole Polytechnique Promotion X2000, Rapport De Stage D'Option Scientifique	(NO DATE)
	34	Riebau, Rhianna A., « Photoluminescence Spectroscopy of Strained InGaAs/GaAs Structures », Thesis Paper, 2001	(NO MONTH)
✓	35	"Module 4: System Overview", Etch Systems – Unity II: Field Engineer Level I	(NO DATE)
508	36	U.S. Patent Application No.: 10/608,091 File Date: June 30, 2003 Attorney Docket Number: 015290-682 Inventor: Steger	

Examiner Signature	Stanley P. Ruchnick	Date Considered	2005/MAY 16
-----------------------	---------------------	--------------------	-------------